

## Supplementary Information for

### **Electrostatic Control of Excitonic Photoluminescence from Both A and B Excitons in Monolayer Molybdenum Disulfide**

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#### **S1. CVD Synthesis of monolayer MoS<sub>2</sub>**

Monolayer MoS<sub>2</sub> on the Si/SiO<sub>2</sub> substrate was grown by using CVD technique in the a furnace with double temperature zones. As shown in Fig. S1(a), two alumina boats with sulfur powder (S, ≥99.5%) and molybdenum (VI) oxide (MoO<sub>3</sub>, ≥99%) powder were placed upstream and downstream of the two-zone furnace, respectively. Several SiO<sub>2</sub>/Si substrates (dimensions of 10 mm × 50 mm × 1 mm) were placed faced-down on the MoO<sub>3</sub> boat. The temperatures of two-zone furnace were controlled by heating-set system program. High-purity argon gas (Ar) was introduced into the quartz tube with a flow rate of 100~200 sccm during the growth process. The growth temperature was set to 850~870 °C and growth time was about 10~20 minutes for monolayer MoS<sub>2</sub> in our growth system at an nearly atmospheric pressure. The monolayer MoS<sub>2</sub> flakes with different quality can be achieved through changing the Mo:S ratio of precursor and the gas flow rate. For the growth of S-rich monolayer MoS<sub>2</sub>, 200 mg sulfur powder and 5 mg MoO<sub>3</sub> powder were used as precursors with an Ar flow rate of 100 ~ 150 sccm. For the growth of Mo-rich monolayer MoS<sub>2</sub>, 200 mg sulfur powder and 10 mg MoO<sub>3</sub> powder were used as precursors, and the Ar gas flow rate was 150 sccm. Fig. S1(b–c) shows the optical microscopy images of the CVD-grown S-rich and Mo-rich monolayer MoS<sub>2</sub> on SiO<sub>2</sub>/Si substrates.

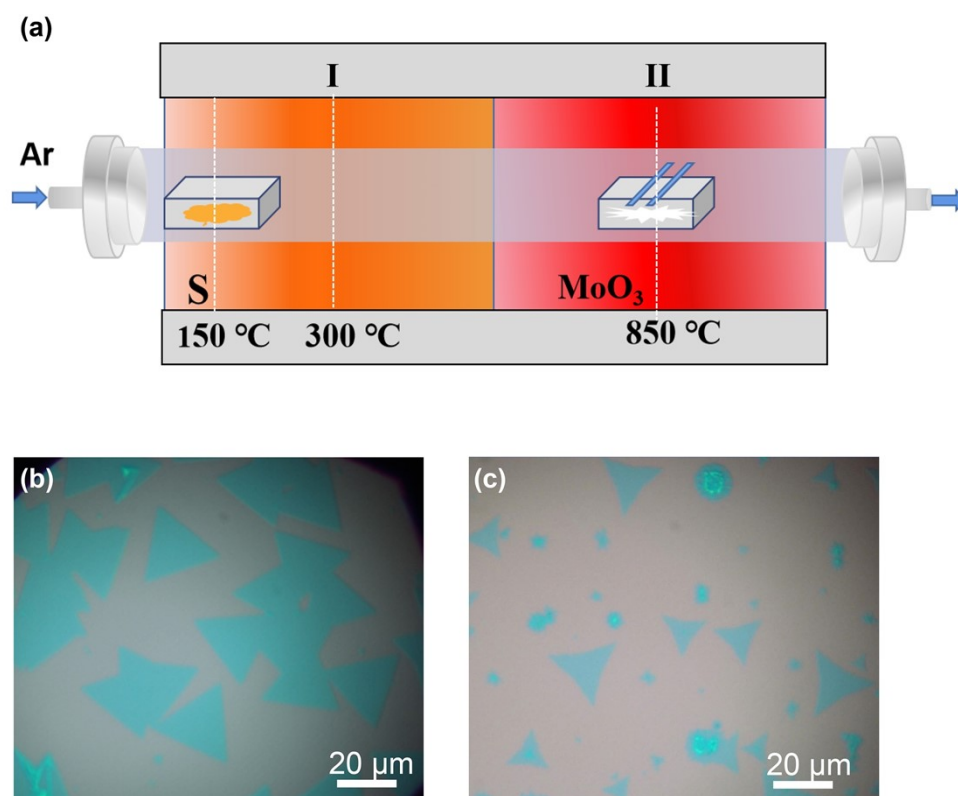


Fig. S1 (a) Setup schematic diagram for the monolayer  $\text{MoS}_2$  growth by CVD method in a two-zone furnace; (b–c) Optical microscopy image of the CVD-grown S-rich and Mo-rich monolayer  $\text{MoS}_2$  on  $\text{SiO}_2/\text{Si}$  substrates.

## S2. Morphology and surface potential of S-rich and Mo-rich monolayer $\text{MoS}_2$

The morphology, surface potential mapping and line profiles for the monolayer  $\text{MoS}_2$  samples with Au electrode on  $\text{SiO}_2/\text{Si}$  substrate are shown in Fig. S2. The contact potential difference (CPD) of  $\text{MoS}_2$  was measured with the Scanning Kelvin Probe in air ambient. In principle, the measured CPD is the difference in work function between the sample surface and the probe:  $eV_{\text{CPD}} = \Phi_{\text{tip}} - \Phi_{\text{sample}}$ , where  $\Phi_{\text{tip}}$  is the known work function of reference tip and  $\Phi_{\text{sample}}$  is the work function of the sample. To investigate the surface potential difference of different  $\text{MoS}_2$  on  $\text{Si}/\text{SiO}_2$  substrate, Au films with a thickness of  $\sim 40$  nm were used as references. The measured surface potential difference between the S-rich  $\text{MoS}_2$  monolayer and Au was  $\sim -44$  mV, while that between Mo-rich  $\text{MoS}_2$  and Au was  $\sim 52$  mV. It indicated that the S-rich  $\text{MoS}_2$  exhibited a higher work function and lower electron density than that of the Mo-rich  $\text{MoS}_2$ .

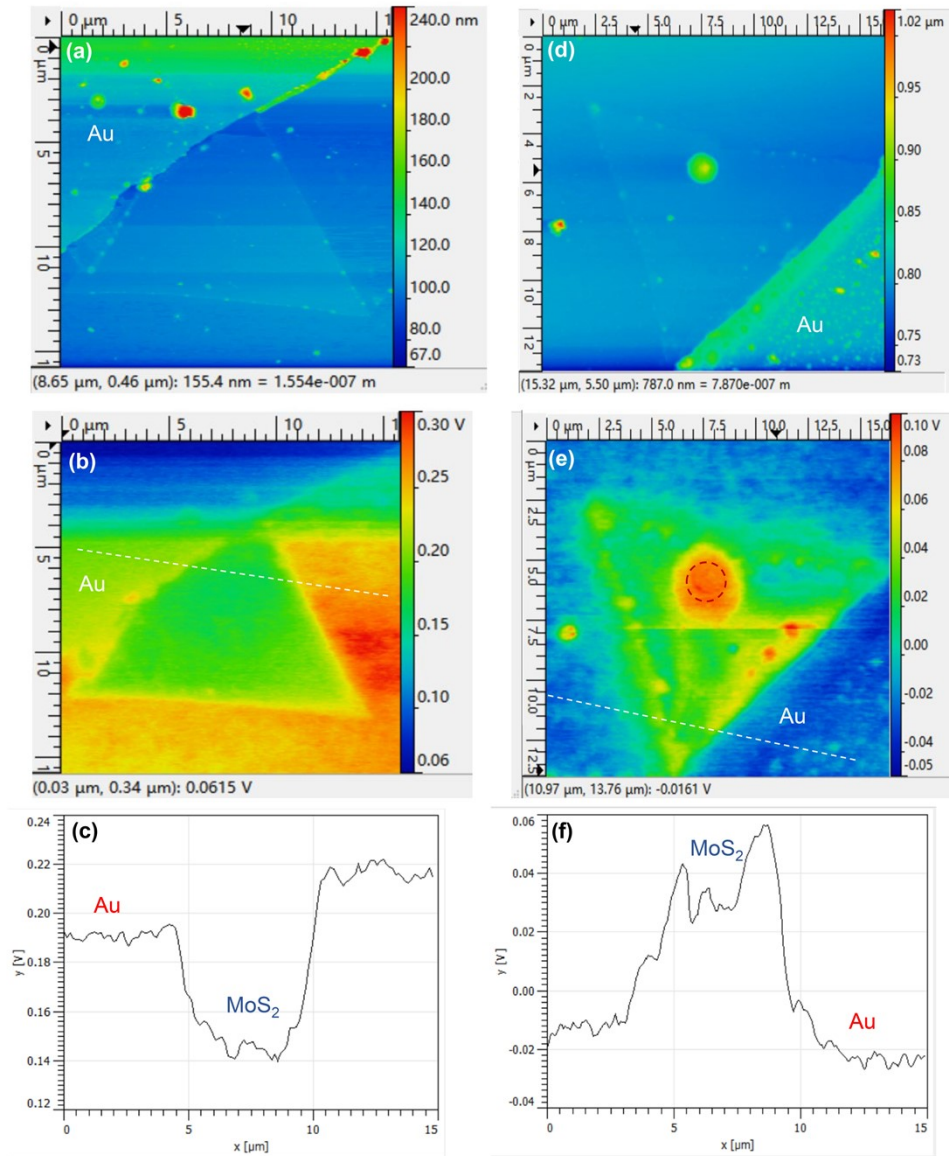


Fig. S2 Morphology, surface potential mapping and line profiles for the monolayer MoS<sub>2</sub> samples with Au electrode on SiO<sub>2</sub>/Si substrate: (a-c) S-rich and (c-d) Mo-rich MoS<sub>2</sub>.

It should be noted that the laser power intensity was  $<10^3$  W/cm<sup>2</sup> for PL and Raman spectra measurements. Since the collection time for measurement of each spectra is very short ( $<30$  seconds), there no obvious structure defects induced by the laser irradiation in the monolayer MoS<sub>2</sub>. Only when the laser excitation last for a long time, additional structure defects can be produced<sup>1</sup>. As shown in Fig. S2 (e), the red dash circles represented the region of continuous laser irradiation for 30 minutes on MoS<sub>2</sub> with laser power intensity of  $2.4 \times 10^3$  W/cm<sup>2</sup> (three times as the power intensity for PL measurements). The continuous laser irradiation led to an increase of 40~50 mV in the  $V_{CPD}$  for the Mo-rich MoS<sub>2</sub>, which inferred an increase of defect density and a decrease of work function.

### S3. Statistical PL intensity ratio for the S-rich and Mo-rich monolayer MoS<sub>2</sub>

The statistical data were obtained from more than 10 tests of PL spectra for the S-rich and Mo-rich MoS<sub>2</sub> samples, which are similar to that in Fig. 3 and Fig. 4. The estimated statistical value of PL intensity ratio for both the S-rich and Mo-rich MoS<sub>2</sub> with the error bars are shown in Fig. S3.

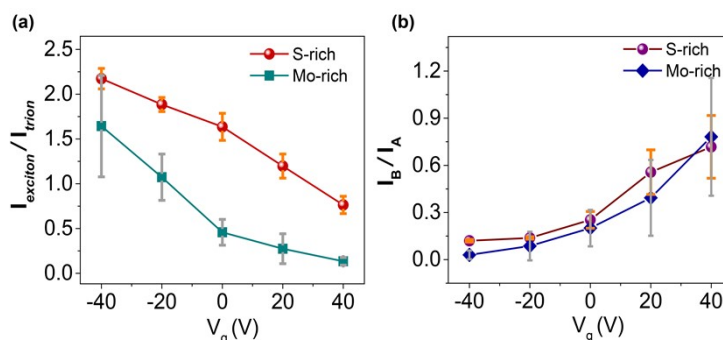


Fig. S3 Statistical PL intensity ratio for the S-rich and Mo-rich MoS<sub>2</sub>: (a)  $I_{\text{exciton}}/I_{\text{trion}}$ , (b)  $I_B/I_A$

### S4. Statistical PL intensity ratio for the S-rich and Mo-rich monolayer MoS<sub>2</sub>

The S-rich MoS<sub>2</sub> sample on SiO<sub>2</sub>/Si was doped by spin-coating PEDOT:PSS and was dried naturally in air. After doped by PEDOT:PSS, the sulfur vacancies can be healed spontaneously by the sulfur adatom clusters through a PSS-induced hydrogenation<sup>2</sup>. The PL emission were measured under the same condition as that of the S-rich and Mo-rich monolayer MoS<sub>2</sub>. Fig. S4 shows the PL spectra and integrated PL intensity of different excitons (A<sup>0</sup>, A<sup>-</sup> and B) at different  $V_g$ . After PEDOT:PSS spin coating on the CVD-grown MoS<sub>2</sub>, the trion PL of doped MoS<sub>2</sub> showed a weak dependence on  $V_g$ , similar to the observation of a PL less sensitive to  $V_g$  in the reported works.

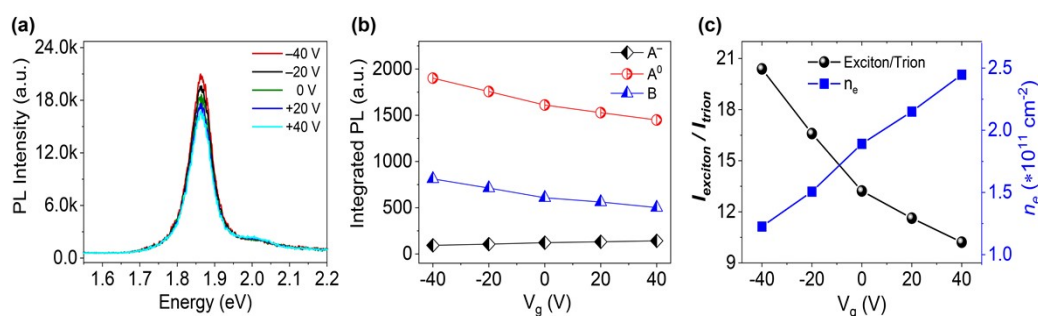


Fig. S4 Gate-dependent PL properties of the S-rich monolayer MoS<sub>2</sub> sample after PEDOT:PSS doping: (a–b) PL spectra and integrated PL intensity of A<sup>0</sup>, A<sup>-</sup>, and B excitons; (c)  $I_{\text{exciton}}/I_{\text{trion}}$  ratio versus  $V_g$ , and calculated electron density versus  $V_g$ .

## References

- <sup>1</sup> H. M. Oh, G. H. Han, H. Kim, J. J. Bae, M. S. Jeong and Y. H. Lee, *ACS Nano*, 2016, **10**, 5230–5236.
- <sup>2</sup> X. Zhang, Q. Liao, S. Liu, Z. Kang, Z. Zhang, J. Du, F. Li, S. Zhang, J. Xiao, B. Liu, Y. Ou, X. Liu, L. Gu and Y. Zhang, *Nature Commun.*, 2017, **8**, 15881.